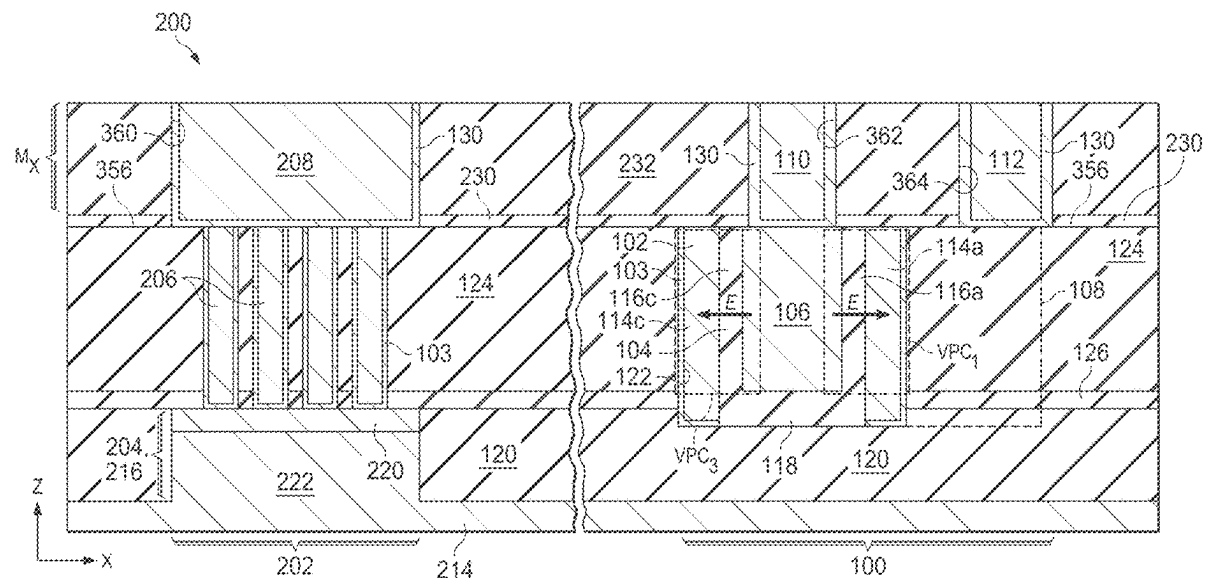
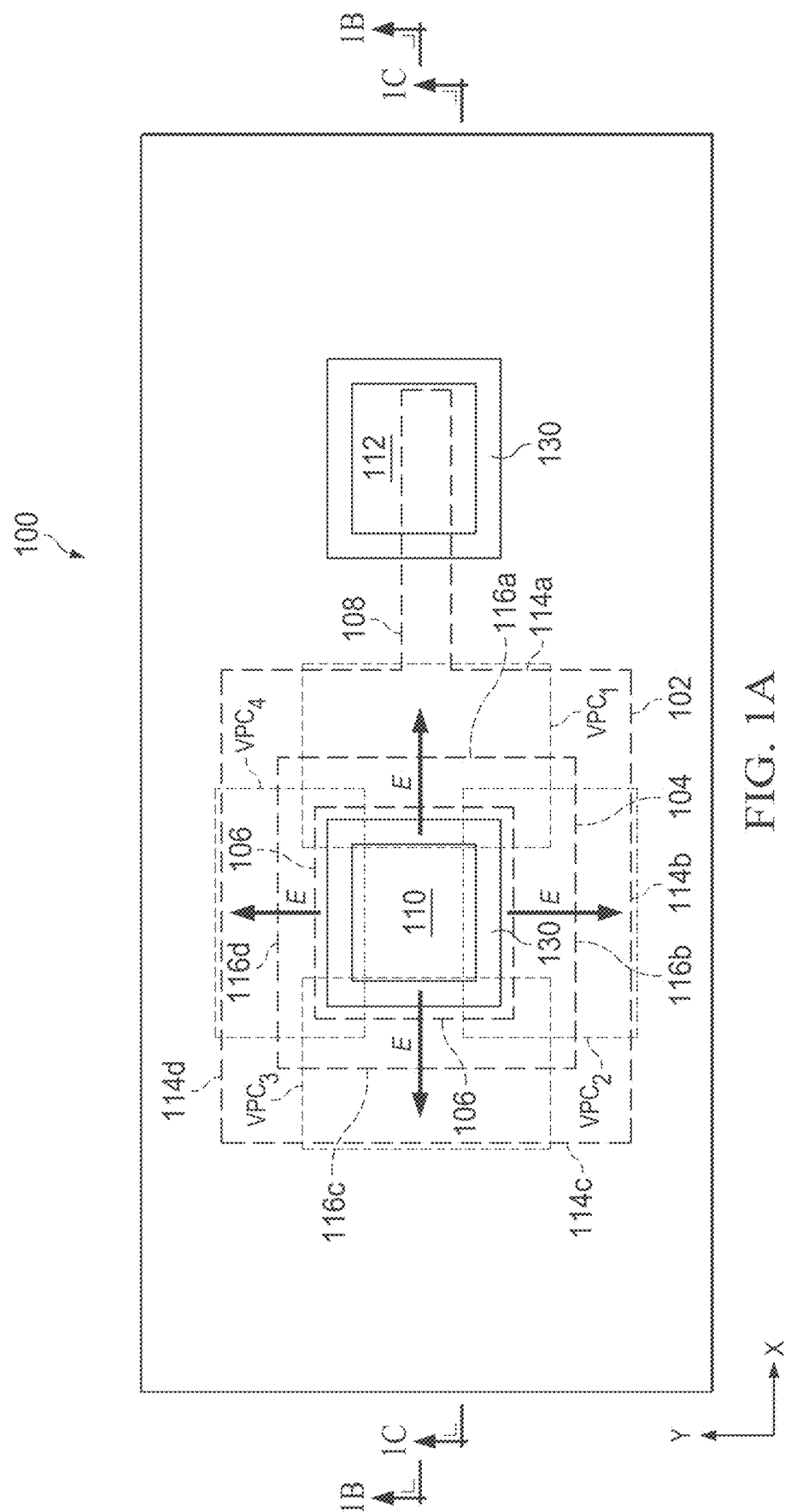
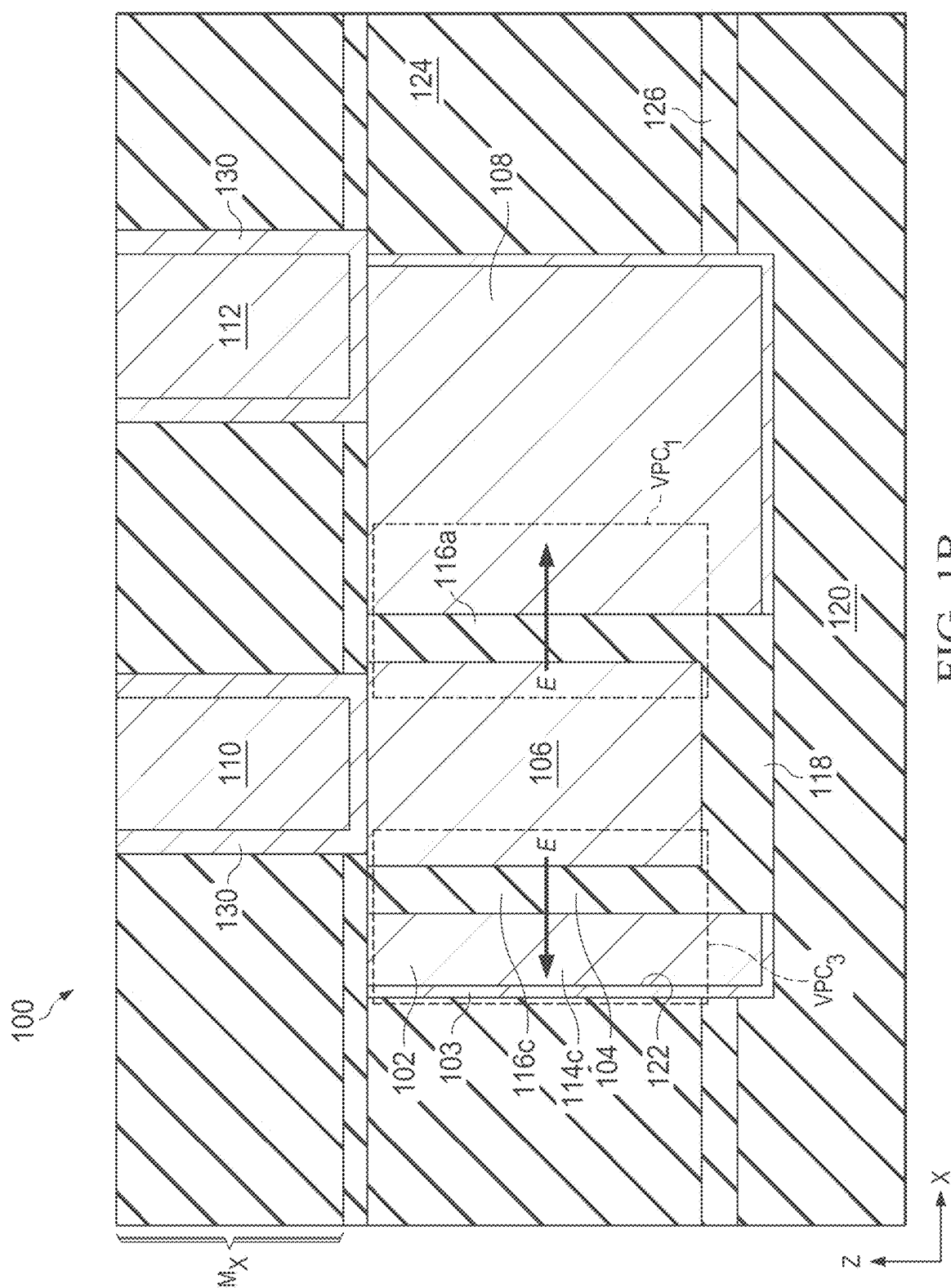
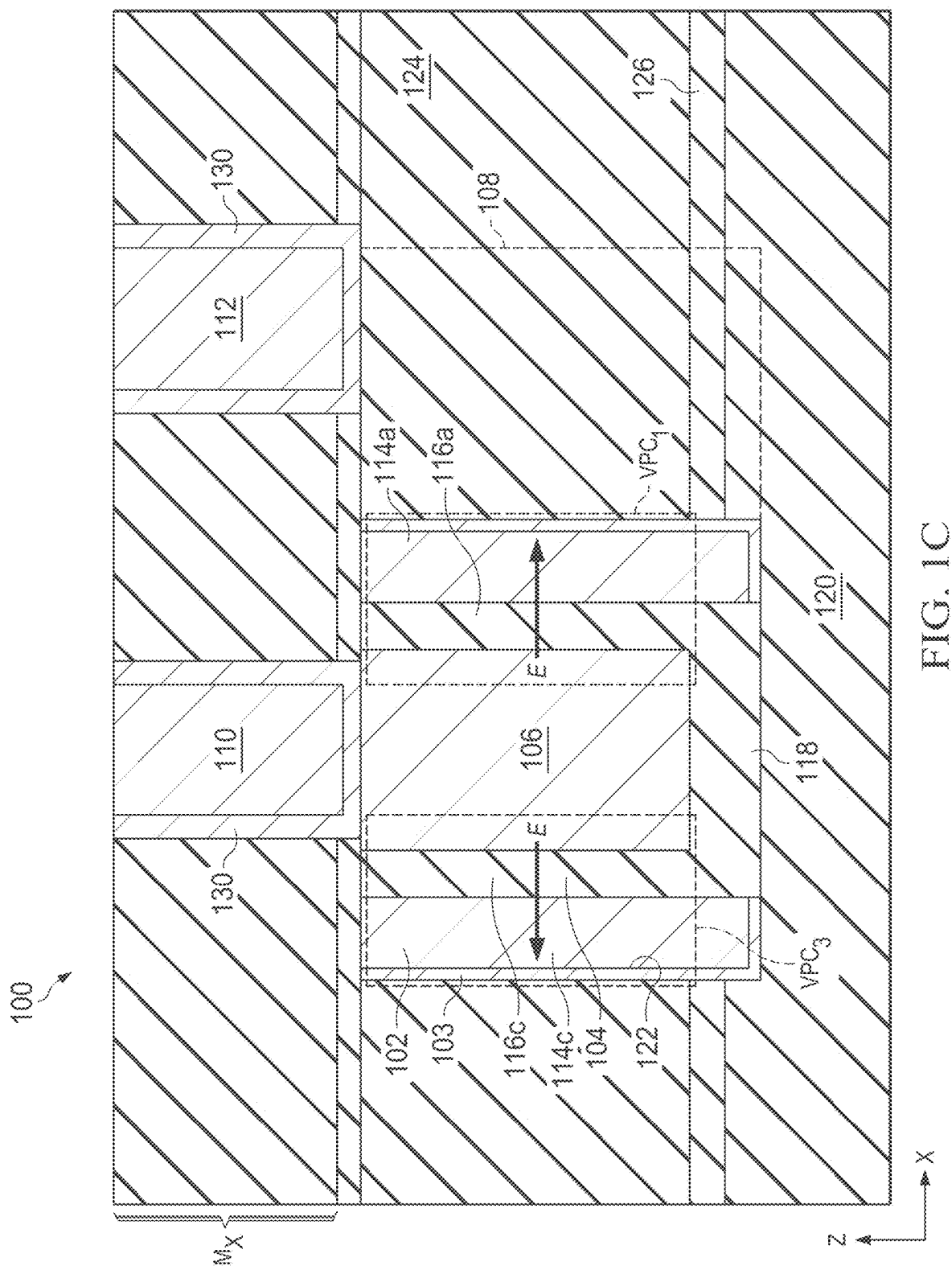


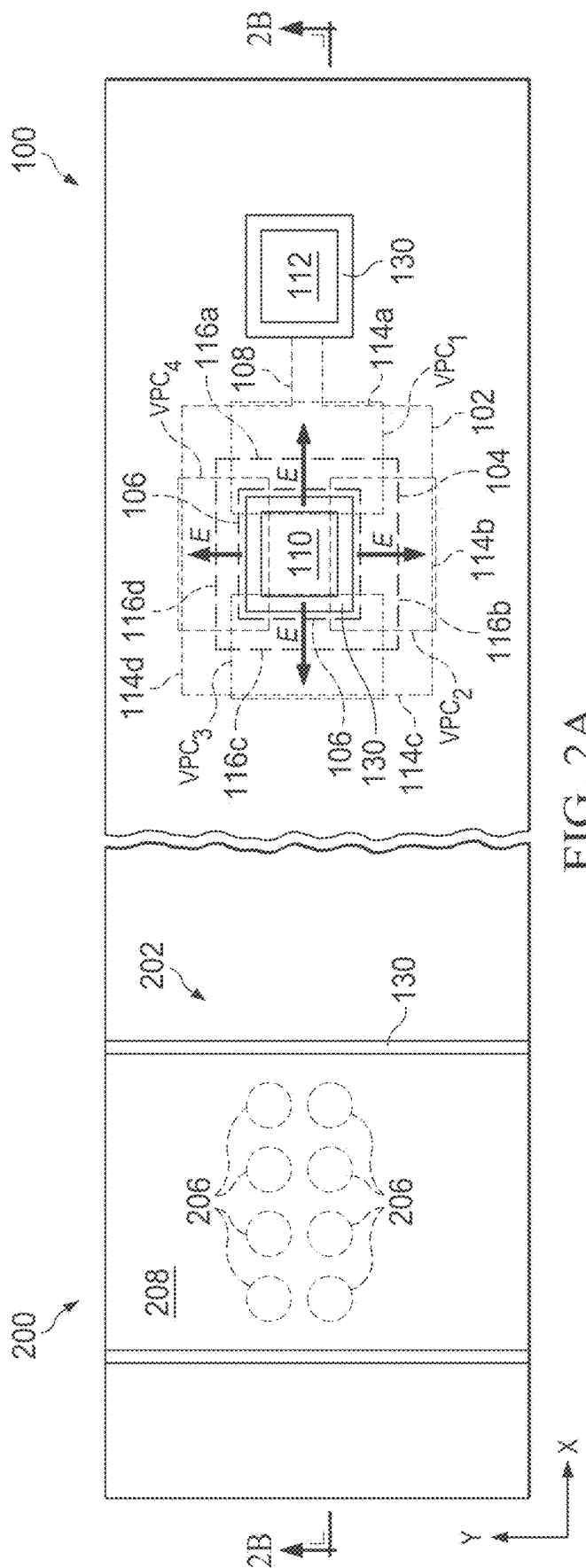
(43) **Pub. Date:** **Aug. 14, 2025**

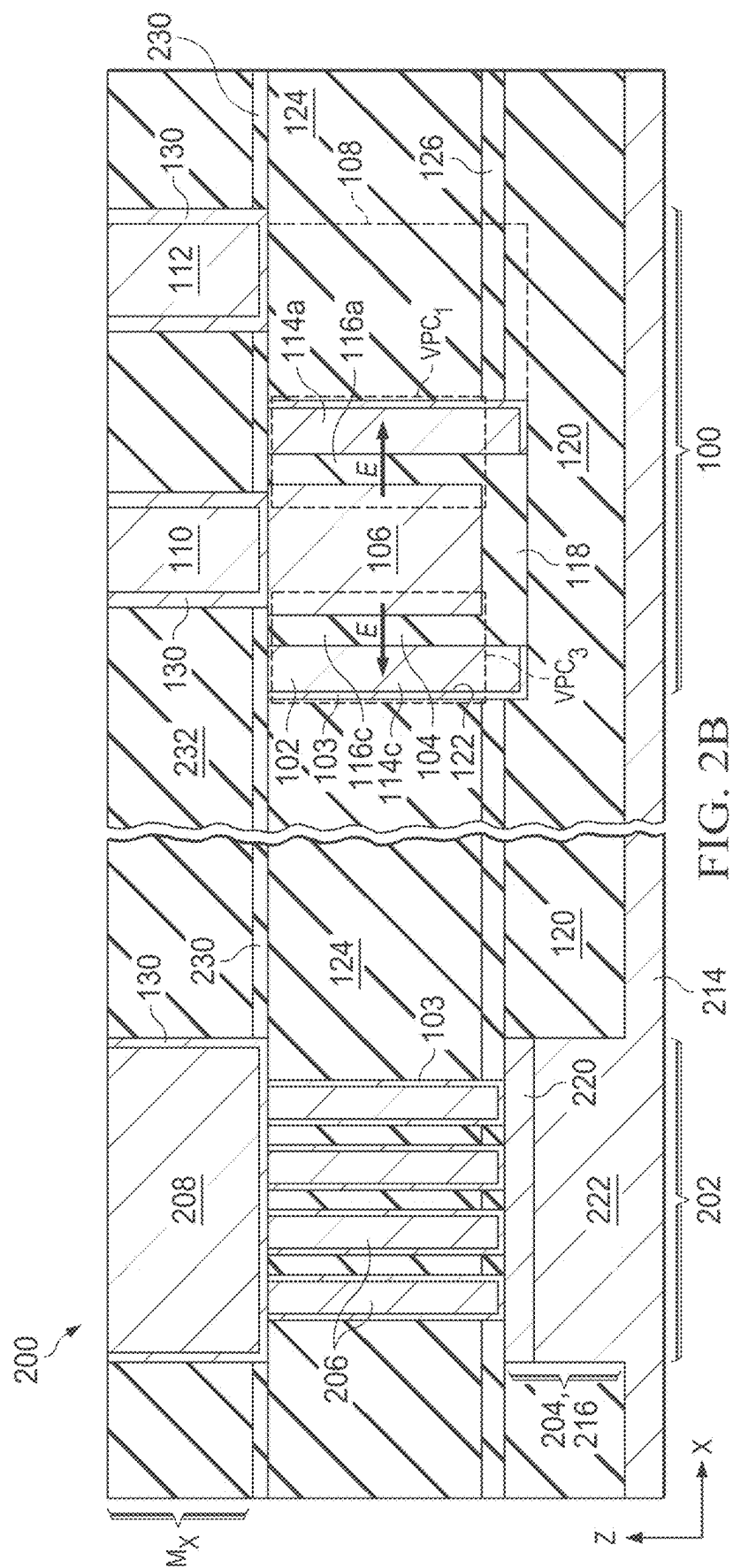


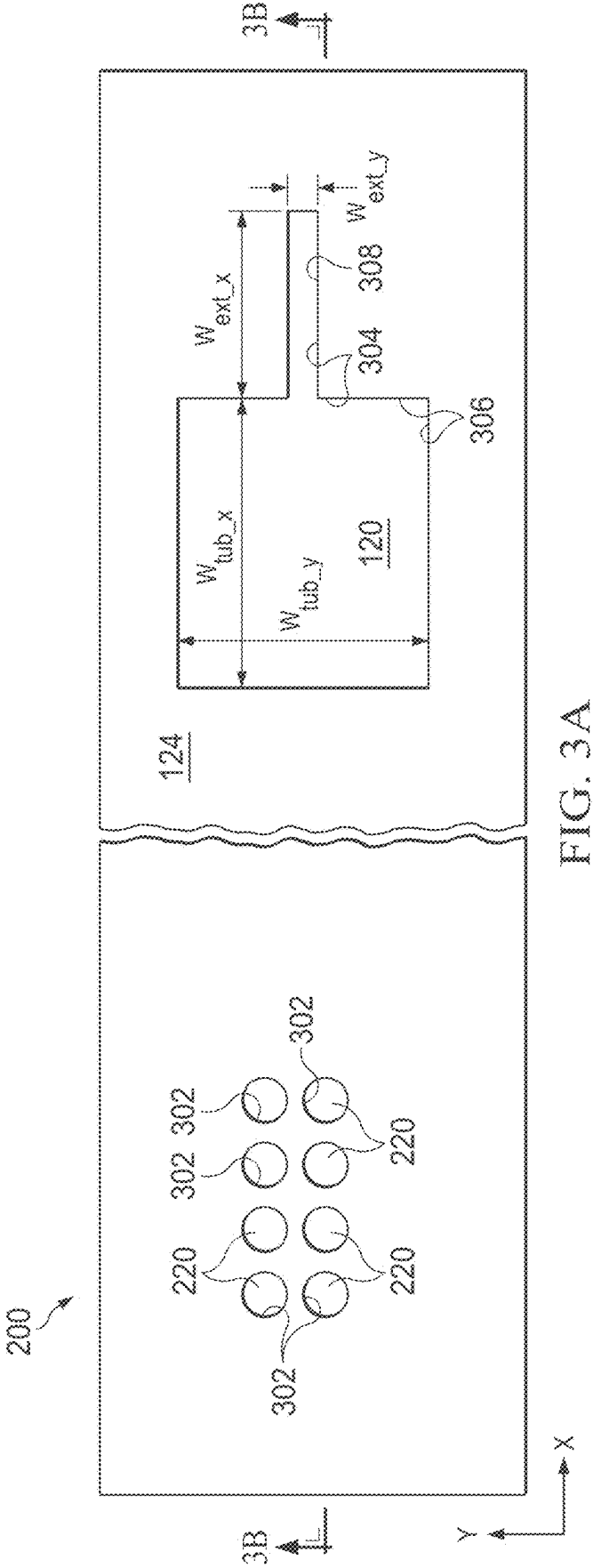


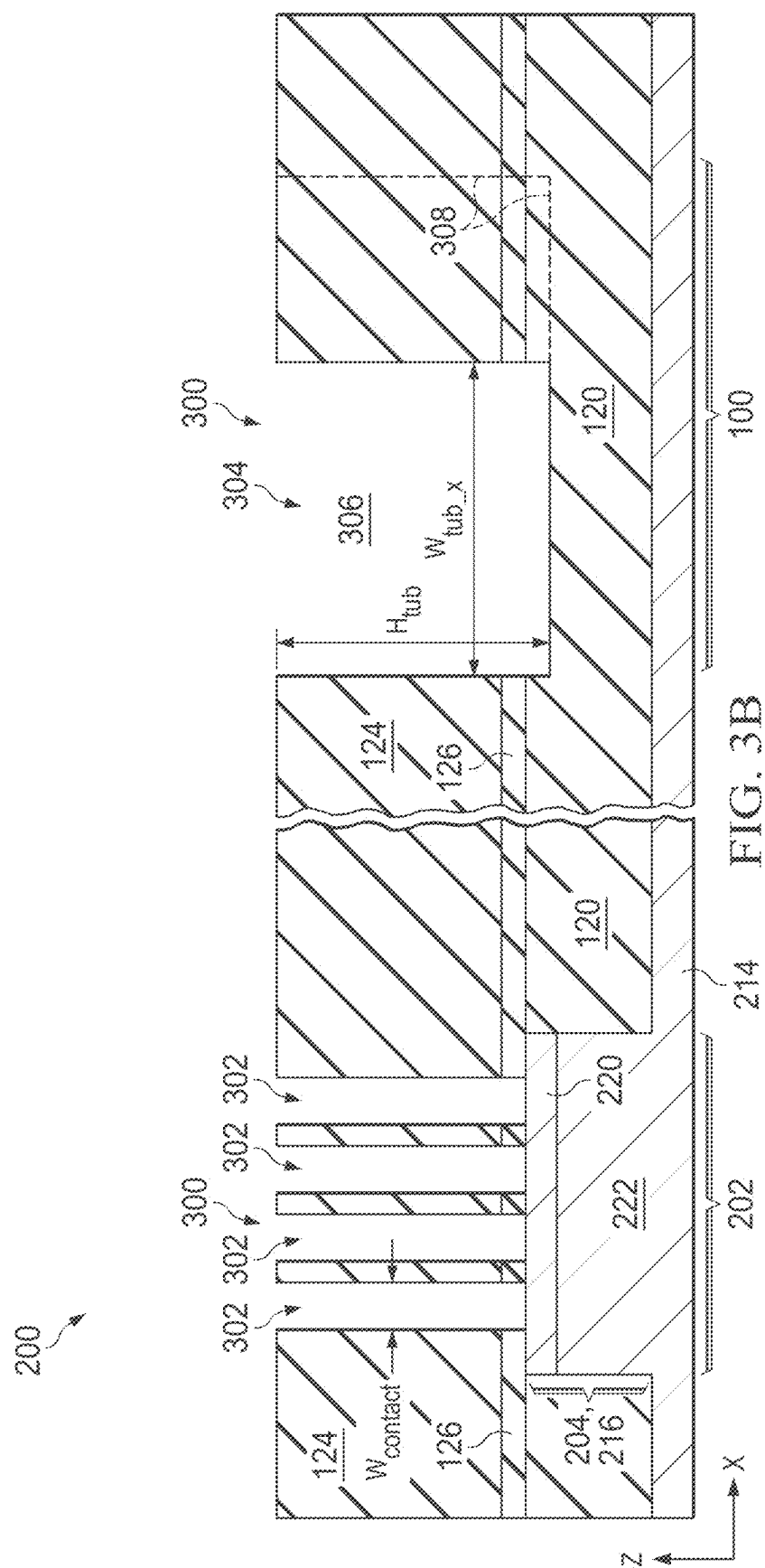
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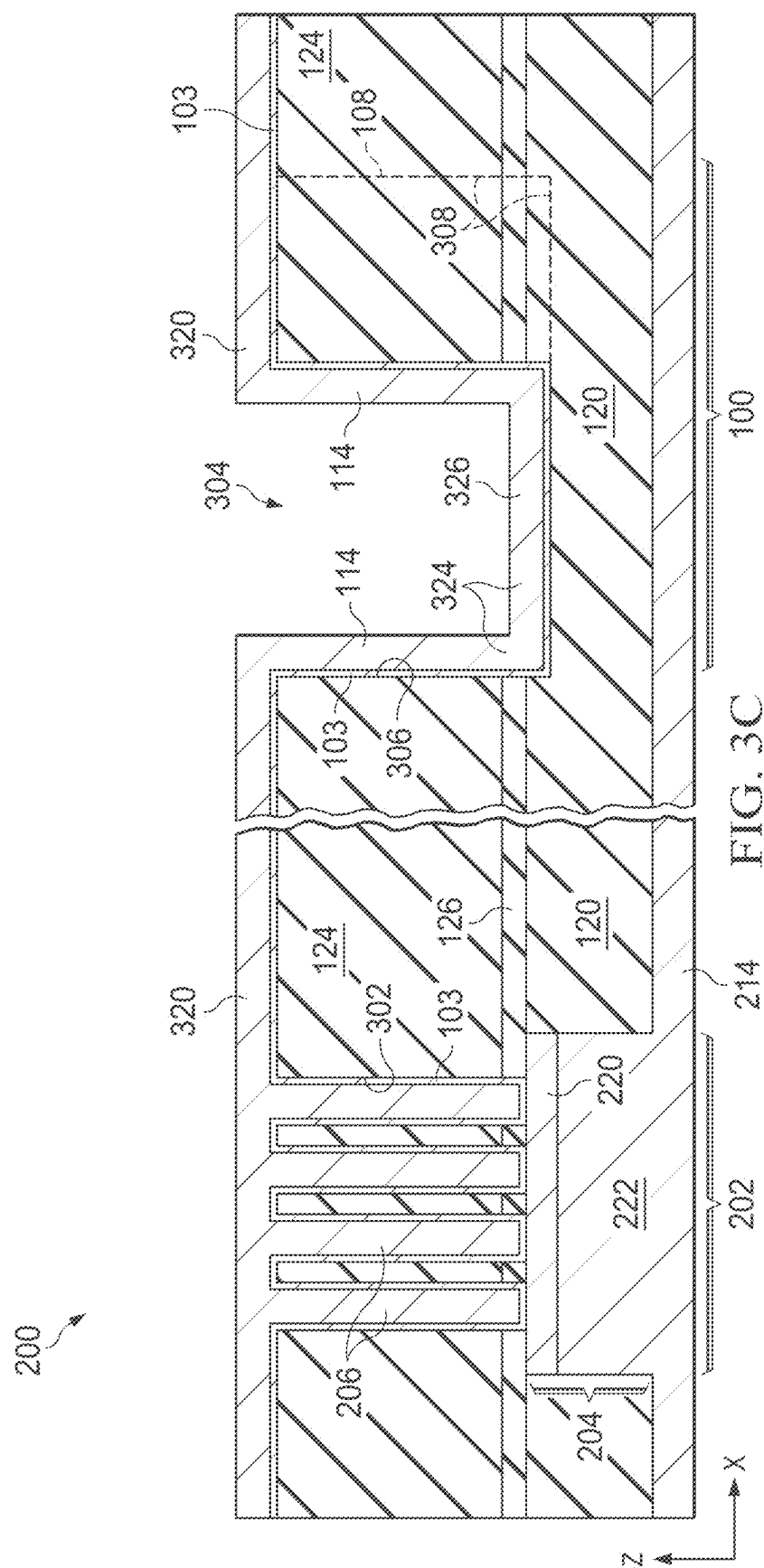












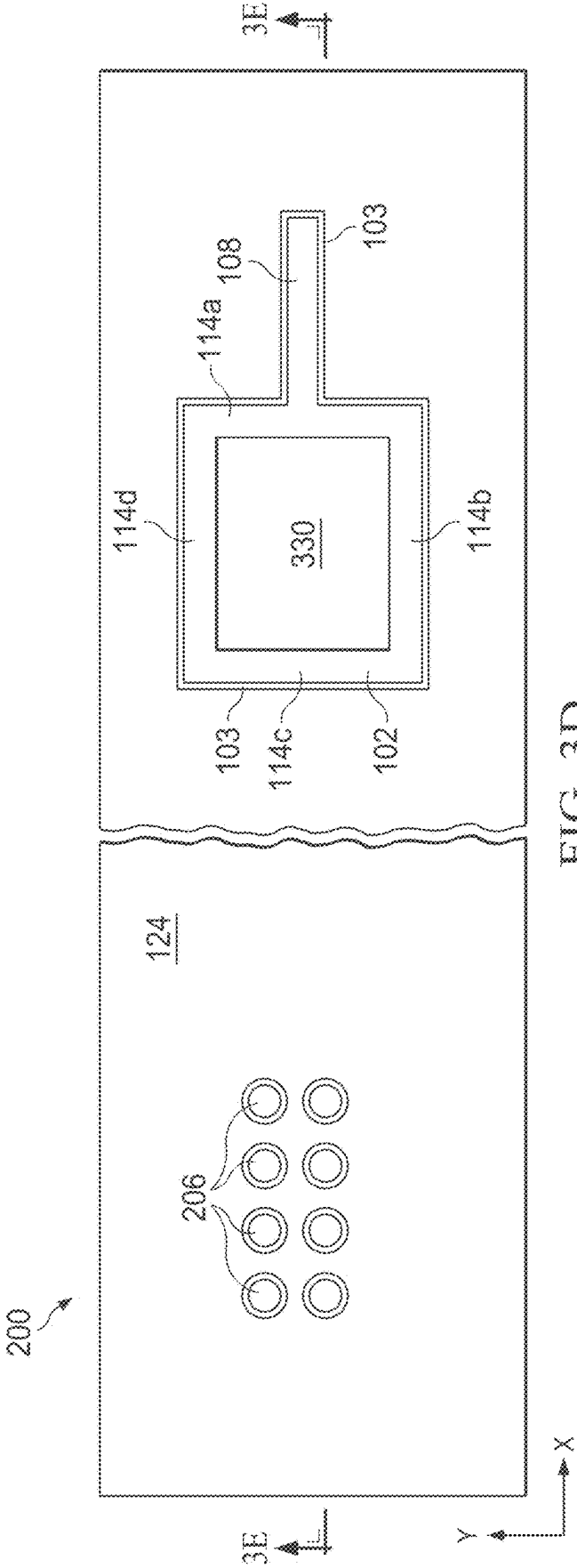
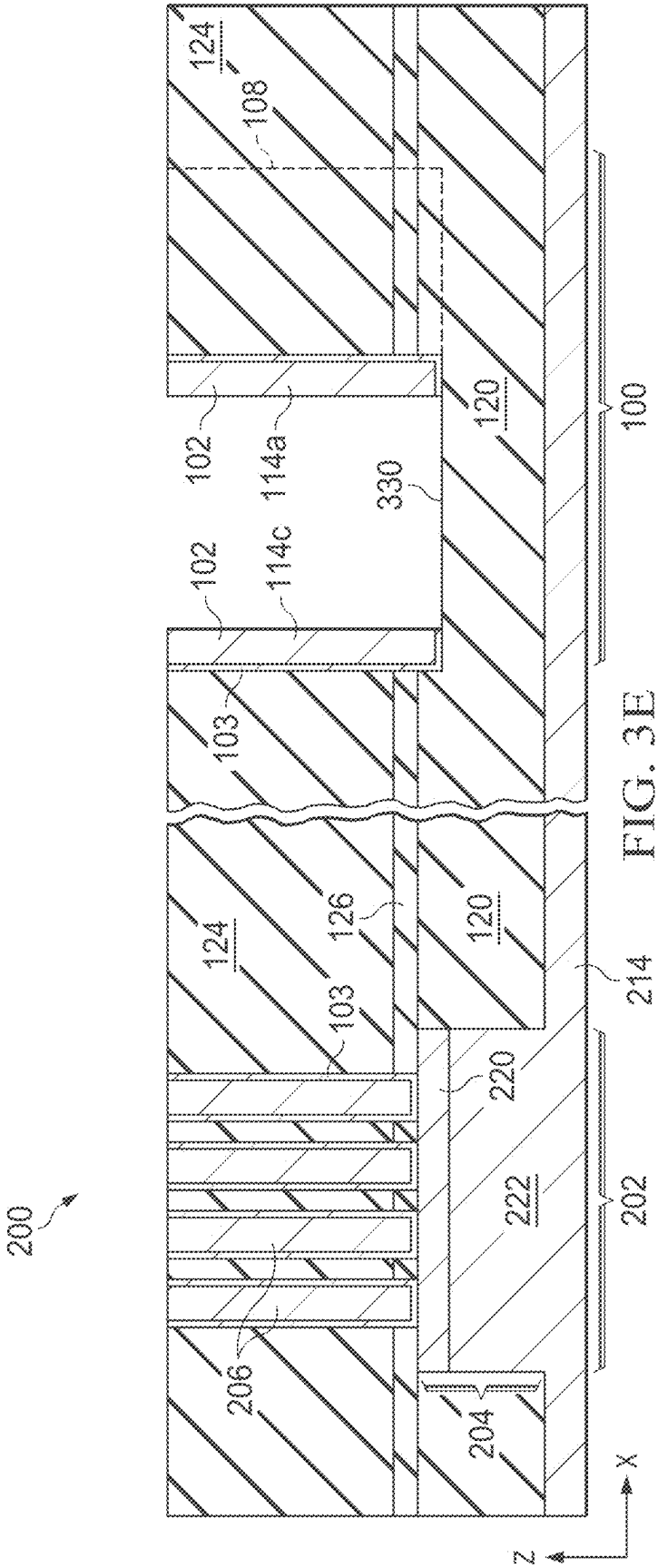


FIG. 3D



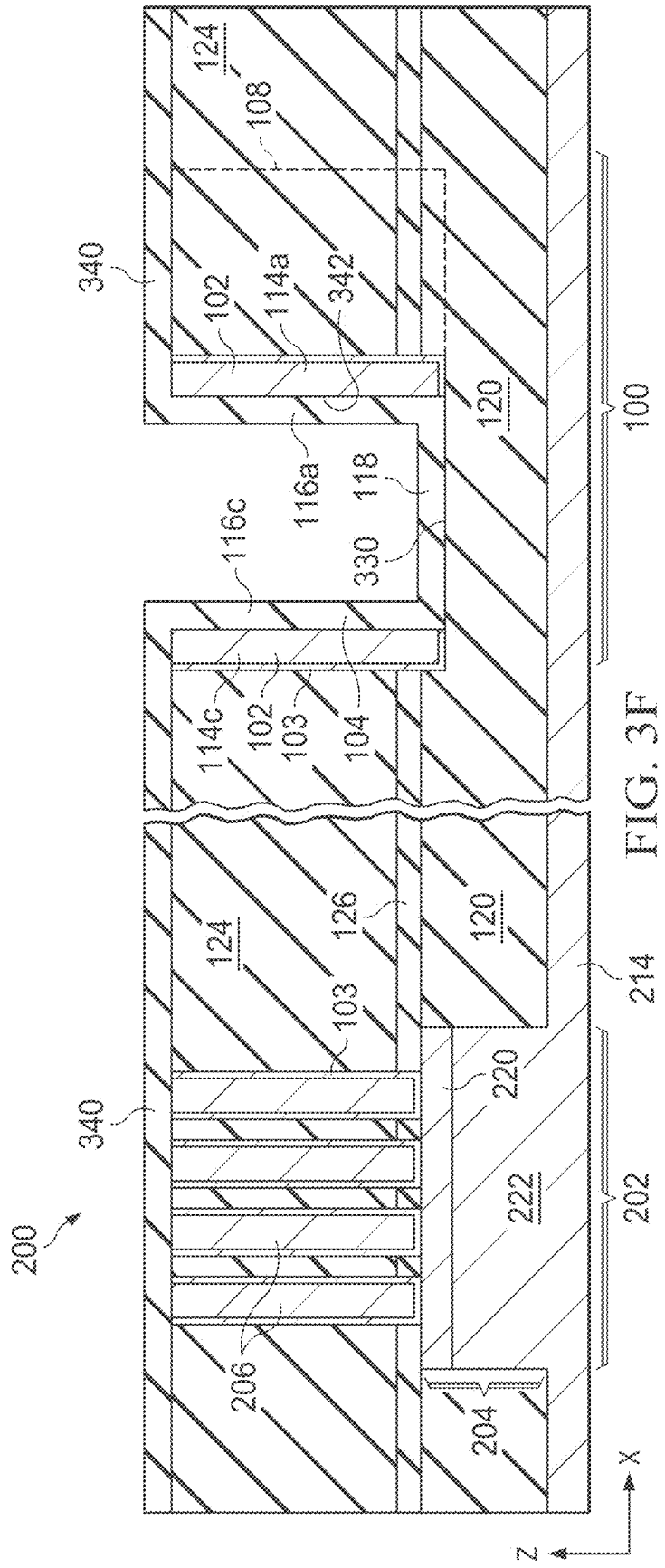
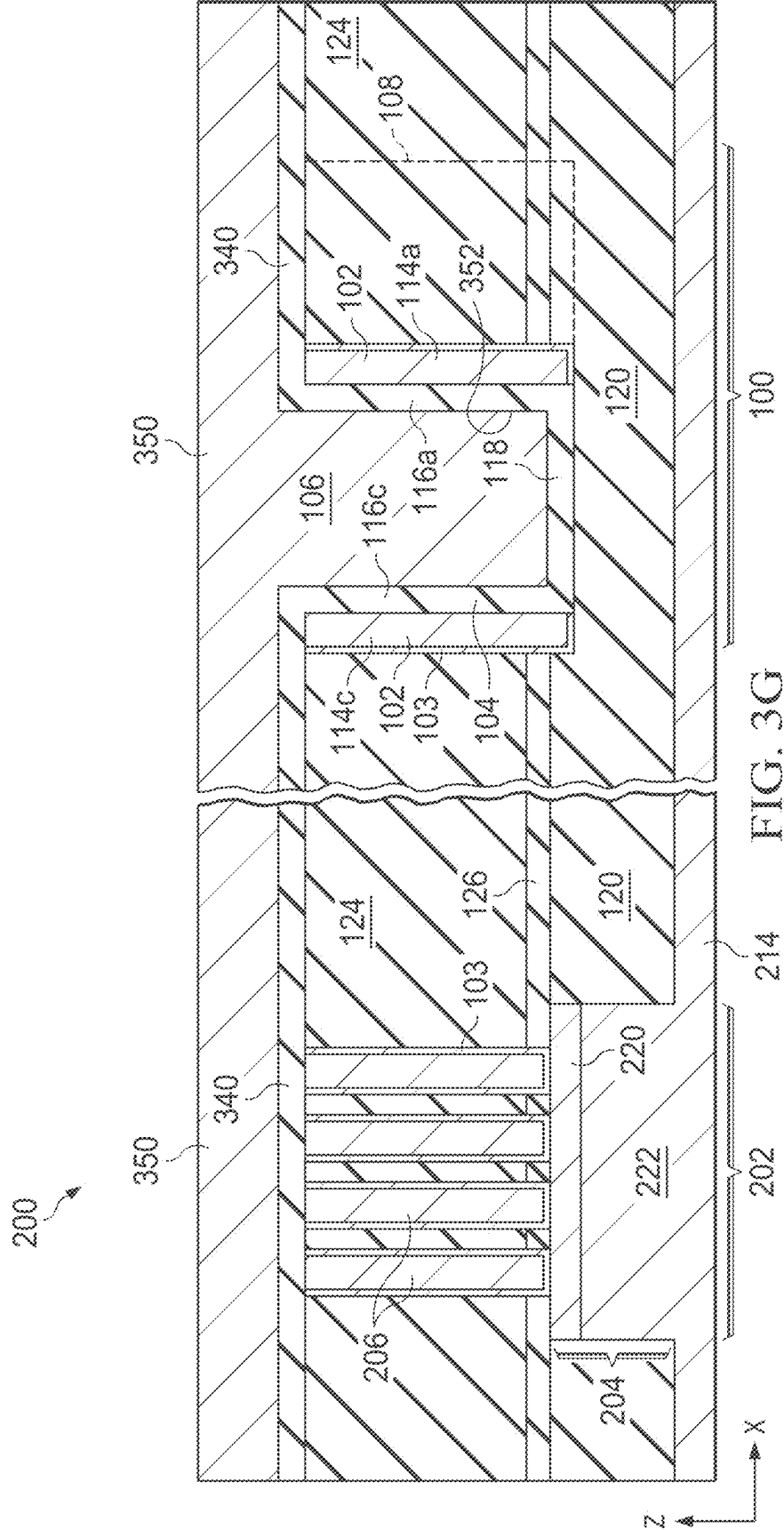


FIG. 3F



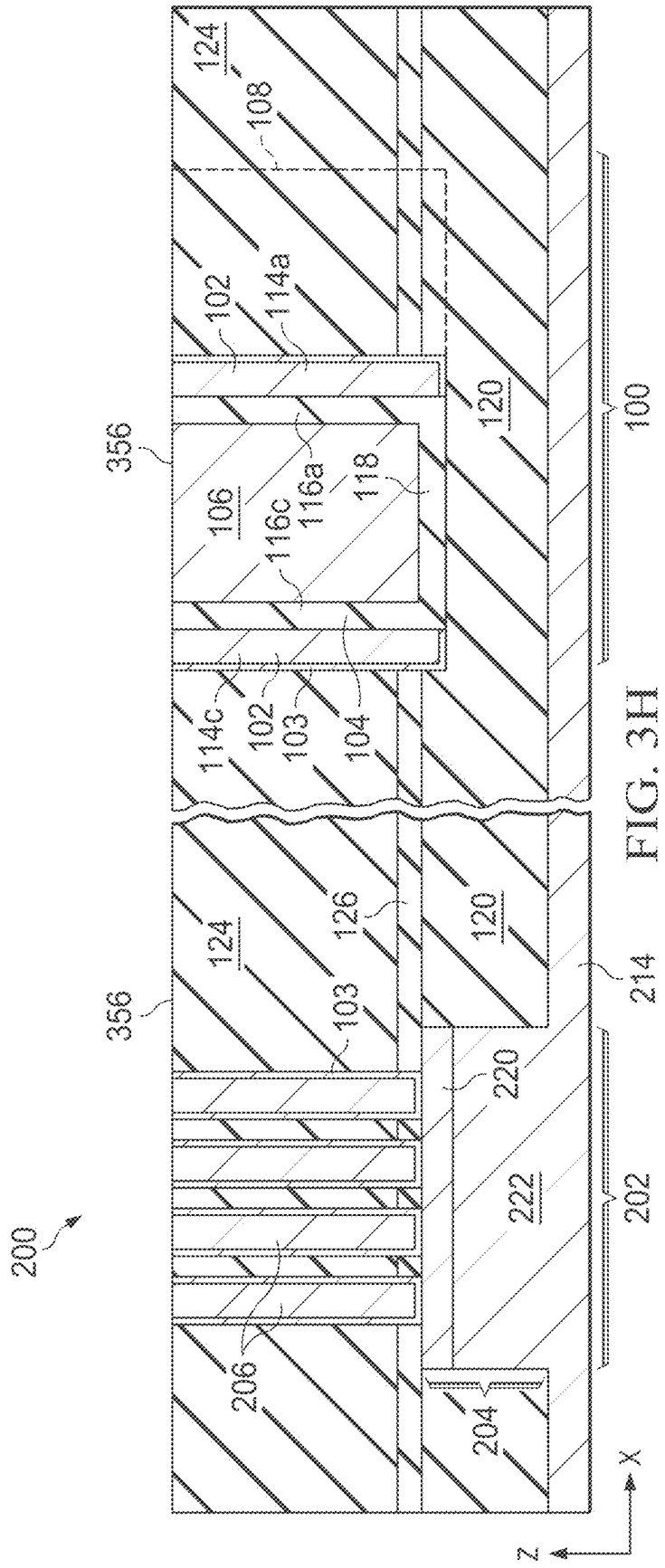
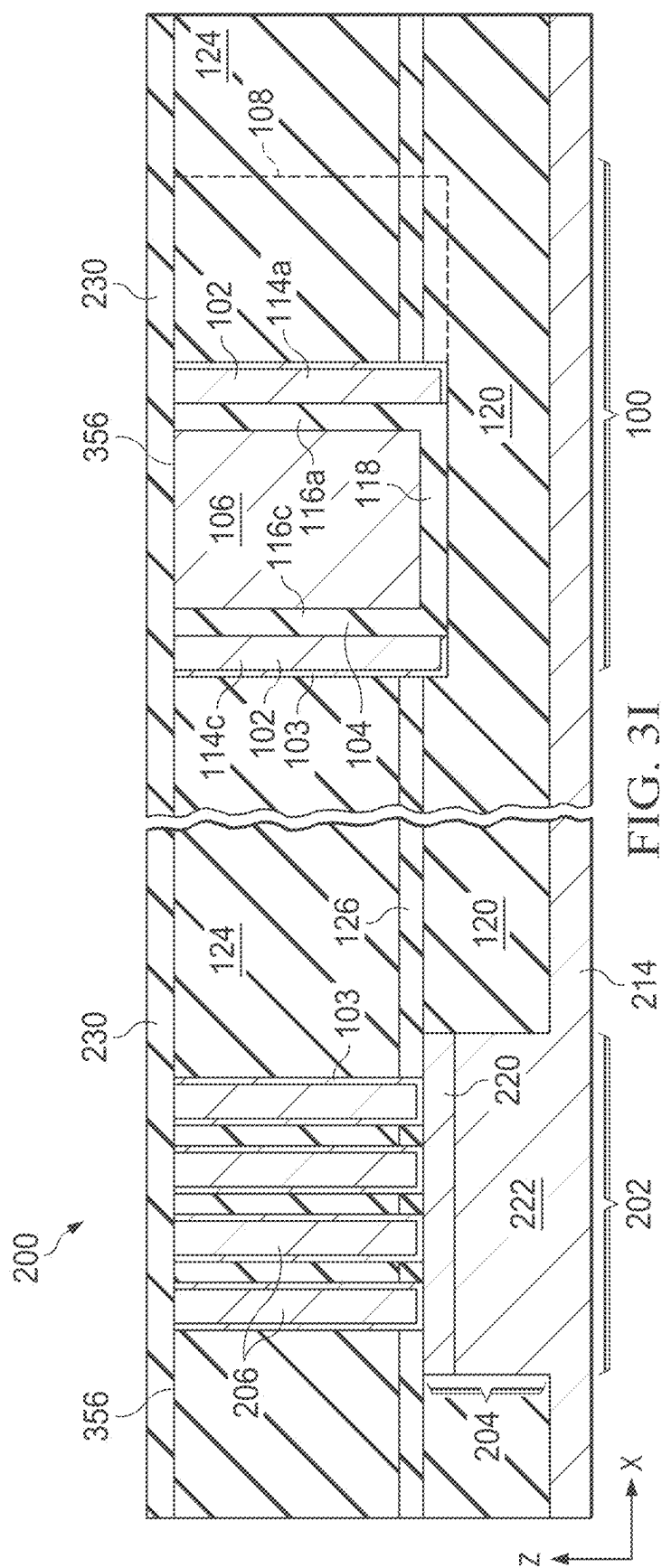
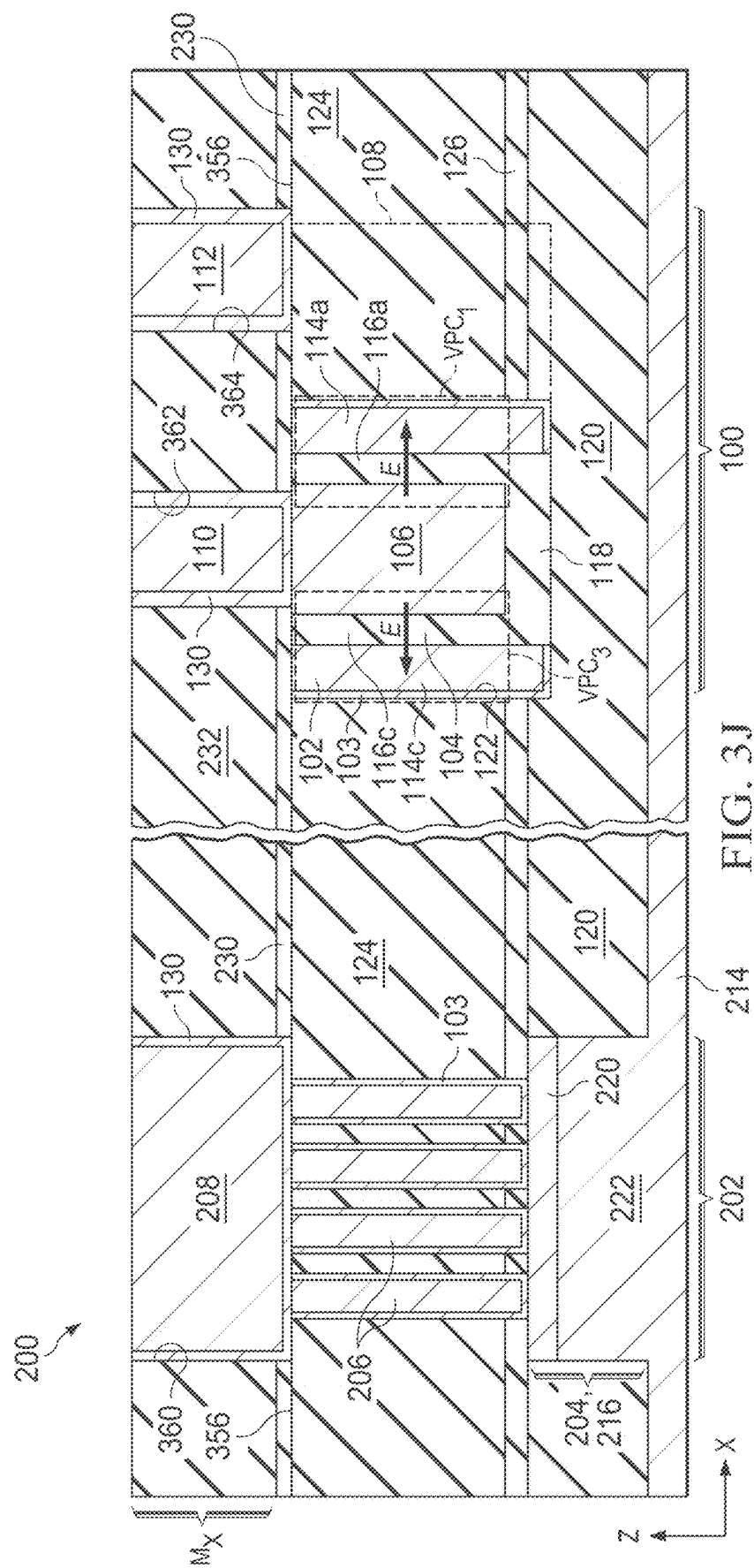


FIG. 3H





METAL-INSULATOR-METAL (MIM) CAPACITOR MODULE WITH OUTER ELECTRODE EXTENSION

RELATED PATENT APPLICATION

[0001] This application claims priority to commonly owned U.S. Provisional Patent Application No. 63/313,410 filed Feb. 24, 2022, the entire contents of which are hereby incorporated by reference for all purposes.

TECHNICAL FIELD

[0002] The present disclosure relates to metal-insulator-metal (MIM) capacitors formed in integrated circuit (IC) devices, and more particularly, to an MIM capacitor module with an outer electrode extension.

BACKGROUND

[0003] Integrated capacitors are key analog components in analog/mixed signal/RF-CMOS circuits. Two types of integrated capacitors are MOM (Metal-Oxide-Metal lateral flux) capacitors and MIM (Metal-Insulator-Metal) capacitors, each with respective advantages and disadvantages.

[0004] In a typical MOM capacitor, the capacitor plates (electrodes) are defined by laterally adjacent metal lines formed on one or multiple metal layers (e.g., multiple interconnect layers), which capacitor plates define a lateral electric field (thus the name lateral flux capacitor). MOM capacitors may be formed at low (or no) additional cost with respect to a background integrated circuit structure, as they often utilize existing interconnect wiring. However, MOM capacitors may be less robust and may exhibit poor matching for analog circuits (e.g., matching device characteristics such as resistance and capacitance, as compared with other types of capacitors), and are generally incompatible with low-k dielectrics.

[0005] In contrast, a typical MIM capacitor includes capacitor plates (electrodes) that extend horizontally, i.e., parallel to the device substrate (e.g., silicon substrate), thus defining a vertical electric field. MIM capacitors typically exhibit better performance than MOM capacitors due to lower resistance, better matching for analog circuits, and/or better signal/noise characteristics. However, MIM capacitors are typically more expensive than MOM capacitors, as the construction of a MIM capacitor typically requires at least one additional photomask process to the background IC fabrication process.

[0006] There is a need for improved MIM capacitors, for example MIM capacitors constructed with no additional masks added to the respective background integrated circuit fabrication process.

SUMMARY

[0007] Improved MIM capacitor modules are disclosed. As used herein, a "MIM capacitor module" includes the fundamental elements of an MIM capacitor, e.g., an insulator (dielectric) arranged between conductive electrodes (e.g., conductive plates), and may also include certain related elements, e.g., conductive elements providing electrical contact to the conductive electrodes.

[0008] In some examples, a MIM capacitor module includes an outer electrode, an insulator, an inner electrode, an outer electrode extension structure, an inner electrode contact element, and an outer electrode contact element. The

outer electrode includes multiple vertically-extending outer electrode sidewalls. The insulator is formed in an opening defined by the multiple vertically-extending outer electrode sidewalls, and includes multiple vertically-extending insulator sidewalls. The inner electrode is formed in an interior opening defined by the insulator, such that respective vertically-extending insulator sidewalls are arranged between the inner electrode and respective vertically-extending outer electrode sidewalls.

[0009] The outer electrode extension structure extends laterally from a particular vertically-extending outer electrode sidewall, in a lateral direction away from the inner electrode. The inner electrode contact element is electrically connected to the inner electrode, and the outer electrode contact element is electrically connected to the outer electrode extension structure. In some examples, the inner electrode contact element and outer electrode contact element are formed in a common (i.e., same) metal layer, for example a metal-1 interconnect layer.

[0010] The inner electrode is capacitively coupled to each vertically-extending outer electrode sidewall through a respective vertically-extending insulator sidewall, to effectively define multiple (e.g., four) vertical-plate capacitor units, each vertical-plate capacitor unit including (a) a vertically-extending dielectric region, defined by a respective vertically-extending insulator sidewall, arranged between (b) a pair of vertically-extending capacitor plates, defined by the inner electrode and a respective vertically-extending outer electrode sidewall, such that each vertical-plate capacitor unit creates a horizontally-extending electric field (E-field), e.g., extending parallel to a device substrate (e.g., silicon wafer substrate).

[0011] In some examples, the MIM capacitor module is formed free of structures that effectively define a horizontal plate capacitor unit, i.e., structures that create a vertically-extending electric field. For example, the outer electrode may include the multiple vertically-extending outer electrode sidewalls, effectively defining multiple vertically-extending capacitor plates, but may substantially omit any laterally-extending elements that may act as a horizontally-extending capacitor plate. In some examples, the outer electrode is constructed by a process including depositing a conformal metal layer that forms an outer electrode cup including a plurality of vertically-extending outer electrode sidewalls extending upwardly from a laterally-extending outer electrode cup base, and subsequently removing (e.g., etching) the laterally-extending outer electrode cup base and other laterally-extending portions of the conformal metal layer, leaving the vertically-extending outer electrode sidewalls.

[0012] In some examples, by removing the laterally-extending outer electrode cup base to form the MIM capacitor module effectively including vertical-plate capacitor units but no horizontal-plate capacitor units, the resulting electrical field characteristics of the MIM capacitor module may be simplified, e.g., as compared with a MIM capacitor modules including a cup-shaped outer electrode (i.e., wherein a horizontal-plate capacitor unit is effectively defined between the laterally-extending outer electrode cup base and a bottom surface of the inner electrode). This simplification of the electrical field characteristics of the MIM capacitor module may be desirable or advantageous in analog circuits, for example where it may be important or advantageous to

construct pairs of MIM capacitor modules having precisely matching electrical characteristics.

[0013] In addition, by removing the laterally-extending outer electrode cup base, unwanted electrical field corner effects (at corners between the laterally-extending outer electrode cup base and vertically-extending outer electrode sidewalls) may be reduced or eliminated, which may increase the breakdown voltage of the MIM capacitor module.

[0014] In some examples, the MIM capacitor module may be constructed using a damascene process without added photomask layers, as compared with a background IC fabrication process.

[0015] In some examples, the MIM capacitor module may be constructed concurrently with elements of an IC component structure, e.g., contact structures for providing an electrical contact to active components, e.g., transistors, and allow compact device design.

[0016] One aspect provides an MIM capacitor module including an outer electrode, an insulator, an inner electrode, an outer electrode extension structure, an inner electrode contact element, and an outer electrode contact element. The outer electrode comprises a plurality of vertically-extending outer electrode sidewalls. The insulator is formed in an opening defined by the plurality of vertically-extending outer electrode sidewalls, the insulator comprising a plurality of vertically-extending insulator sidewalls. The inner electrode is formed in an interior opening defined by the plurality of vertically-extending insulator sidewalls. Respective ones of the plurality of vertically-extending insulator sidewalls are arranged between the inner electrode and a respective one of the plurality of vertically-extending outer electrode sidewalls. The outer electrode extension structure extends laterally from a particular vertically-extending outer electrode sidewall of the plurality of vertically-extending outer electrode sidewalls. The inner electrode contact element and outer electrode contact element are formed in a metal layer, wherein the inner electrode contact element is electrically connected to the inner electrode, and the outer electrode contact element is electrically connected to the outer electrode extension structure.

[0017] In some examples, the particular vertically-extending outer electrode sidewall is elongated in a first lateral direction, and the outer electrode extension structure is elongated in a second lateral direction perpendicular to the first lateral direction.

[0018] In some examples, the outer electrode has a closed-loop perimeter defined by the plurality of vertically-extending outer electrode sidewalls, and the insulator has a closed-loop perimeter defined by the plurality of vertically-extending insulator sidewalls.

[0019] In some examples, the insulator has a cup-shaped structure including the plurality of vertically-extending insulator sidewalls extending upwardly from a laterally-extending insulator base.

[0020] In some examples, the laterally-extending insulator base lies directly on a dielectric region.

[0021] Another aspect provides a device including an MIM capacitor module and an IC component structure. The MIM capacitor module includes an outer electrode, an insulator, an inner electrode, an outer electrode extension structure, an inner electrode contact element, and an outer electrode contact element. The outer electrode comprises a plurality of vertically-extending outer electrode sidewalls

formed from a conformal metal. The insulator is formed in an opening defined by the plurality of vertically-extending outer electrode sidewalls, and comprises a plurality of vertically-extending insulator sidewalls. The inner electrode is formed in an interior opening defined by the plurality of vertically-extending insulator sidewalls. Respective ones of the plurality of vertically-extending insulator sidewalls are arranged between the inner electrode and a respective one of the plurality of vertically-extending outer electrode sidewalls. The outer electrode extension structure extends laterally from a particular vertically-extending outer electrode sidewall of the plurality of vertically-extending outer electrode sidewalls. The inner electrode contact element and outer electrode contact element are formed in a metal layer, wherein the inner electrode contact element is electrically connected to the inner electrode, and the outer electrode contact element is electrically connected to the outer electrode extension structure. The IC component structure includes an IC component, a vertically extending IC component contact formed from the conformal metal, the vertically-extending IC component contact formed above the IC component and electrically connected to the IC component, and an IC component connection element formed in the metal layer and electrically connected to the vertically-extending IC component contact.

[0022] In some examples, the IC component comprises a silicided polysilicon structure.

[0023] In some examples, the IC component comprises a transistor component.

[0024] In some examples, the particular vertically-extending outer electrode sidewall is elongated in a first lateral direction, and the outer electrode extension structure is elongated in a second lateral direction perpendicular to the first lateral direction.

[0025] In some examples, the outer electrode has a closed-loop perimeter defined by the plurality of vertically-extending outer electrode sidewalls, and the insulator has a closed-loop perimeter defined by the plurality of vertically-extending insulator sidewalls.

[0026] In some examples, the insulator has a cup-shaped structure including the plurality of vertically-extending insulator sidewalls extending upwardly from a laterally-extending insulator base.

[0027] In some examples, the laterally-extending insulator base lies directly on a dielectric region.

[0028] Another aspect provides a method. The method includes forming an outer electrode opening in a dielectric region, the outer electrode opening including a tub opening region and an extension opening region extending laterally from the tub opening region. The method further includes depositing a conformal metal layer over the dielectric region and extending down into the outer electrode opening to form (a) an outer electrode cup in the tub opening region and (b) an outer electrode extension structure in the extension opening region. The outer electrode cup includes a laterally-extending outer electrode cup base and a plurality of vertically-extending outer electrode sidewalls extending upwardly from the laterally-extending outer electrode cup base. The outer electrode extension structure extends laterally from a particular vertically-extending outer electrode sidewall of the plurality of vertically-extending outer electrode sidewalls. The method further includes depositing an insulator layer forming a cup-shaped insulator in an opening defined by the plurality of vertically-extending outer elec-

trode sidewalls, the cup-shaped insulator including a laterally-extending insulator base and a plurality of vertically-extending insulator sidewalls extending upwardly from the laterally-extending insulator base. The method further includes depositing an inner electrode layer over the insulator layer and extending into an opening defined by the cup-shaped insulator. The method further includes performing a planarization process to remove upper portions of the insulator layer and inner electrode layer, wherein a remaining portion of the inner electrode layer defines an inner electrode. The method further includes forming a metal layer including (a) an inner electrode contact element electrically connected to the inner electrode and (b) an outer electrode contact element electrically connected to the outer electrode extension structure.

[0029] In some examples, the method includes performing an etch process to remove the laterally-extending outer electrode cup base prior to depositing the insulator layer.

[0030] In some examples, forming the outer electrode opening in the dielectric region exposes a dielectric surface at a bottom of the tub opening region, and depositing the insulator layer forming the cup-shaped insulator comprises depositing the laterally-extending insulator base on the exposed dielectric surface at the bottom of the tub opening region.

[0031] In some examples, the method includes, prior to forming the metal layer, depositing an etch stop layer on a planarized surface defined by the planarization process.

[0032] In some examples, the method includes forming an integrated circuit (IC) component contact opening in the dielectric region and laterally spaced apart from the outer electrode opening, the IC component contact opening exposing an underlying IC component, wherein the deposited conformal metal layer extends down into the IC component contact opening to form a vertically-extending IC component contact, and wherein the metal layer includes (a) the inner electrode contact element electrically connected to the inner electrode, (b) the outer electrode contact element electrically connected to the outer electrode extension structure, and (c) an IC component connection element electrically connected to the IC component contact.

[0033] In some examples, the IC component comprises a silicided polysilicon structure.

[0034] In some examples, the IC component comprises a transistor component.

BRIEF DESCRIPTION OF THE DRAWINGS

[0035] Example aspects of the present disclosure are described below in conjunction with the figures, in which:

[0036] FIG. 1A is a top view and FIGS. 1B and 1C are two side cross-sectional views of an example MIM capacitor module;

[0037] FIG. 2A is a top view and FIG. 2B is a side cross-sectional view showing an example IC structure including the example MIM capacitor module of FIGS. 1A-2B and an example IC component structure, which may be formed concurrently, according to one example; and

[0038] FIGS. 3A-3J show an example method of forming the example IC structure shown in FIGS. 2A and 2B, including the example MIM capacitor module and example IC component structure.

[0039] It should be understood the reference number for any illustrated element that appears in multiple different figures has the same meaning across the multiple figures,

and the mention or discussion herein of any illustrated element in the context of any particular figure also applies to each other figure, if any, in which that same illustrated element is shown.

DETAILED DESCRIPTION

[0040] FIGS. 1A-1C show an example MIM capacitor module 100 according to the present disclosure. In particular, FIG. 1A shows a top view of the MIM capacitor module 100, FIG. 1B shows a first cross-sectional side view of the MIM capacitor module 100 through cut line 1B-1B shown in FIG. 1A, and FIG. 1C shows a second cross-sectional side view of the MIM capacitor module 100 through cut line 1C-1C shown in FIG. 1A. As shown, MIM capacitor module 100 includes (a) an outer electrode 102, (b) an insulator 104, (c) an inner electrode 106, (d) an outer electrode extension structure 108, (e) an inner electrode contact element 110, and (f) an outer electrode contact element 112.

[0041] The outer electrode 102 includes a plurality of vertically-extending outer electrode sidewalls 114a-114d, e.g., extending upwardly from a lower dielectric region 120, e.g., an oxide region formed over a silicon substrate. In this example, the vertically-extending outer electrode sidewalls 114a-114d define a closed-loop perimeter in a horizontal (x-y) plane. The outer electrode 102 may comprise a conformal metal, e.g., tungsten, which may be deposited over a liner 103, e.g., comprising TiN, as discussed below with reference to FIG. 3C. The outer electrode extension structure 108 extends laterally from a particular vertically-extending outer electrode sidewall 114a-114d, in this example vertically-extending outer electrode sidewall 114a. In some examples, the outer electrode extension structure 108 extends perpendicularly from the particular vertically-extending outer electrode sidewall 114a in the x-y plane. In the example shown in FIG. 1A, the outer electrode sidewall 114a is laterally elongated in the y-direction, and the outer electrode extension structure 108 is elongated in the x-direction, i.e., perpendicular to the y-direction elongation of the outer electrode sidewall 114a.

[0042] It should be understood that the term “particular” in the context of “a particular vertically-extending outer electrode sidewall” is used merely for reference and does not imply any distinct characteristic of the particular vertically-extending outer electrode sidewall in relation to the other vertically-extending outer electrode sidewalls.

[0043] The insulator 104 is formed within the closed-loop perimeter defined by the vertically-extending outer electrode sidewalls 114a-114d. The insulator 104 includes a plurality of vertically-extending insulator sidewalls 116a-116d extending upwardly from a laterally-extending insulator base 118 formed on the dielectric region 120. In this example, the vertically-extending insulator sidewalls 116a-116d also define a closed-loop perimeter in a horizontal (x-y) plane. In some examples, the insulator 104 comprises SiN, SiO₂, or a high-k dielectric (e.g., having a dielectric constant greater than 7), for example Al₂O₃, Ta₂O₅, HfO₂, or ZrO₂. The liner 103, outer electrode 102, and insulator 104 may be formed in a tub opening 122 formed in a dielectric region 124, e.g., a pre-metal dielectric region (PMD). In some examples, dielectric region 124 may comprise silicon oxide, phosphorus silicate glass (PSG), or borophosphosilicate glass (BPSG). As discussed below, the tub opening 122

may extend through an (optional) etch stop layer **126**, e.g., a silicon nitride etch stop layer, formed on the lower dielectric region **120**.

[0044] In other examples, insulator **104** may omit the laterally-extending insulator base **118**. Thus, insulator **104** may include vertically-extending insulator sidewalls **116a-116d** extending upwardly from dielectric region **120**, without the laterally-extending insulator base **118**. For example, the laterally-extending insulator base **118** may be removed by an optional etch process, e.g., as discussed below with respect to FIG. 3F.

[0045] The inner electrode **106** is formed in an interior opening defined by the plurality of vertically-extending insulator sidewalls **116a-116d**. In some examples, the inner electrode **106** may comprise Al, Ti, TiN, W, TiW, Co, Ta, TaN, Cu, or any combination thereof, for example, TiN plus Al, TiN plus W, or a Ta/TaN bilayer plus Cu.

[0046] The inner electrode contact element **110** and outer electrode contact element **112** may be formed over a conductive barrier layer **130**, e.g., comprising a barrier layer (e.g., a TaN/Ta bilayer). The inner electrode contact element **110** is electrically connected to the inner electrode **106** (by direct contact or through conductive barrier layer **130**, if present), and the outer electrode contact element **112** is electrically connected to the outer electrode extension structure **108** (by direct contact or through conductive barrier layer **130**, if present). The inner electrode contact element **110** and outer electrode contact element **112** are formed in a common (i.e., same) metal layer M_x , for example a Metal-1 interconnect layer formed from copper.

[0047] As shown in FIGS. 1A-1C, respective vertically-extending insulator sidewalls **116a-116d** are arranged between the inner electrode **106** and respective vertically-extending outer electrode sidewalls **114a-114d**. Thus, the inner electrode **106** is capacitively coupled to each vertically-extending outer electrode sidewalls **114a-114d** through a respective vertically-extending insulator sidewall **116a-116d**, to effectively define four vertical-plate capacitor units, indicated generally at VPC_1 - VPC_4 , each having a vertically-extending dielectric (defined by a respective vertically-extending insulator sidewall **116a-116d**) arranged between a pair of vertically-extending capacitor plates (defined by the inner electrode **106** and a respective vertically-extending outer electrode sidewall **114a-114d**), and each creating a horizontally-extending electric field “E,” extending in the x-direction or y-direction.

[0048] In the example shown in FIGS. 1A-1C, MIM capacitor module **100** includes vertical-plate capacitor units VPC_1 - VPC_4 creating respective horizontally-extending (x-direction or y-direction) electric fields (electric fields E shown in FIGS. 1A-1C), and excludes any horizontal-plate capacitor unit creating a vertically-extending (z-direction) electric field.

[0049] FIGS. 2A and 2B show an example IC structure **200** including the MIM capacitor module **100** shown in FIGS. 1A-1B and an IC component structure **202** formed concurrently, according to one example. In particular, FIG. 2A shows a top view of the example IC structure **200**, and FIG. 2B shows a side cross-sectional view of the example IC structure **200** through cut line 2B-2B shown in FIG. 2A.

[0050] As mentioned above, the MIM capacitor module **100** may be constructed without adding any photomask operations to the background integrated circuit fabrication

process (e.g., the background integrated circuit fabrication process for forming the IC component structure **202** and/or other IC components).

[0051] As discussed above, MIM capacitor module **100** includes outer electrode **102** including vertically-extending outer electrode sidewalls **114a-114d**, insulator **104** including vertically-extending insulator sidewalls **116a-116d**, inner electrode **106**, outer electrode extension structure **108** which extends laterally from the vertically-extending outer electrode sidewall **114a**, inner electrode contact element **110** electrically connected to the inner electrode **106**, and outer electrode contact element **112** electrically connected to the outer electrode extension structure **108**.

[0052] As discussed above, the inner electrode **106** is capacitively coupled to respective vertically-extending outer electrode sidewalls **114a-114d** through respective vertically-extending insulator sidewalls **116a-116d** to effectively define four vertical-plate capacitor units, indicated generally at VPC_1 - VPC_4 , each creating a horizontally-extending electric field “E” extending in the x-direction or y-direction.

[0053] As shown in FIG. 2B, the IC component structure **202** may include an IC component **204**, at least one vertically-extending IC component contact **206** electrically connected to the IC component **204** (by direct contact or through liner **103**, if present), and an IC component connection element **208** electrically connected to the at least one vertically-extending IC component contact **206** (by direct contact or through barrier layer **130**, if present). The IC component **204** may be part of a transistor structure, such as a source or drain region, or any other type of integrated circuit component.

[0054] As shown, the IC component **204** may be formed on, or over, a substrate **214**, e.g., a silicon substrate. In the illustrated example, the IC component **204** comprises a silicided active region **216** adjacent to a shallow trench isolation (STI) field oxide region **120**, which is formed over substrate **214**. The silicided active region **216** may include a metal silicide region **220** formed on an active silicon region **222**. In another example, the IC component **204** may comprise a silicided polysilicon region, e.g., a poly gate of a transistor.

[0055] Etch stop layer **126** may be formed over the lower dielectric region **120** (e.g., STI field oxide), and dielectric region **124** (e.g., PMD region) may be formed over etch stop layer **126**. At least one vertically-extending IC component contact **206**, along with the outer electrode **102**, insulator **104**, inner electrode **106**, and outer electrode extension structure **108** of MIM capacitor module **100**, may be formed in the dielectric region **124** (e.g., PMD region), e.g., using a damascene process as discussed below with respect to FIGS. 3A-3H. Each vertically-extending IC component contact **206** and the outer electrode **102** may be deposited over a liner **103**, e.g., comprising TiN, as discussed below with reference to FIG. 3C.

[0056] The IC component connection element **208**, along with the inner electrode contact element **110** and outer electrode contact element **112** of MIM capacitor module **100**, may be formed in metal layer M_x , for example a Metal-1 interconnect layer comprising copper, aluminum, or other metal. The IC component connection element **208**, inner electrode contact element **110**, and outer electrode contact element **112** may be formed in respective openings formed (etched) in a dielectric region **232** using a damascene process as discussed below with respect to FIG. 3J. Dielec-

tric region **232** may comprise silicon oxide, fluorosilicate glass (FSG), organosilicate glass (OSG), porous OSG, or other low-k dielectrics (e.g., having a dielectric constant k less than 4.0). An upper etch stop layer **230** formed on the dielectric region **124** may be used to control the depth of the openings etched in dielectric region **232**. IC component connection element **208**, inner electrode contact element **110**, and outer electrode contact element **112** may each be formed over conductive barrier layer **130** formed in the respective openings in dielectric region **232**.

[0057] FIGS. 3A-3J show an example method of forming the example IC structure **200** shown in FIGS. 2A and 2B, including the example MIM capacitor module **100** and example IC component structure **202**. In other examples, the example IC component structure **202** may be optional, such that MIM capacitor module **100** may be formed by the process described below but without the elements of IC component structure **202**.

[0058] As shown in FIG. 3A (top view) and FIG. 3B (cross-sectional side view through line 3B-3B shown in FIG. 3A), the example IC component **204** and/or additional IC components (not shown) are formed on the substrate **214**, e.g., a silicon substrate. As discussed above, the example IC component **204** comprises a silicided active region **216** adjacent to STI field oxide region **120**, which is formed over substrate **214**. As discussed above, the silicided active region **216** may include a metal silicide region **220** formed on an active region **222**.

[0059] An etch stop layer **126** may be formed on the lower dielectric region **120** (e.g., STI field oxide), and extending over a top surface of the metal silicide region **220** of the example IC component **204**. In some examples, etch stop layer **126** may comprise a silicon nitride etch stop layer, e.g., having a thickness in the range of 250 Å-750 Å. In other examples the etch stop layer **126** may be omitted.

[0060] Dielectric region **124** (e.g., PMD region) may be formed over etch stop layer **126** (or directly over the lower dielectric region **120** and top surface of the metal silicide region **220** in an example in which the etch stop layer **126** is omitted). In some examples, dielectric region **124** may comprise silicon oxide, phosphorus silicate glass (PSG), or borophosphosilicate glass (BPSG).

[0061] A number of openings **300**, including IC component contact openings **302** and an outer electrode opening **304** may be patterned (using a photomask) and etched in the dielectric region **124**. As shown, IC component contact openings **302** are laterally spaced apart from the outer electrode opening **304**. Outer electrode opening **304** includes a tub opening region **306** and an extension opening region **308** extending laterally from the tub opening region **306**.

[0062] Openings **300** may be formed using a plasma etch or other suitable etch, followed by a resist strip or other suitable process to remove remaining portions of photoresist material. In examples including etch stop layer **126**, the depth of openings **300** may be controlled by the etch stop layer **126**, e.g., to stop at a depth just below the etch stop layer **126** to thereby (a) expose a respective top surface area of the metal silicide region **220** at a bottom of each IC component contact opening **302** and (b) expose a top surface area of the lower dielectric region **120** (e.g., oxide region) at a bottom of the outer electrode opening **304**.

[0063] The IC component contact openings **302** may have a width (or diameter or Critical Dimension (CD)) $W_{contact}$ in both the x-direction and y-direction in the range of 0.1-0.5 μm , for example.

[0064] In contrast, the tub opening region **306** of the outer electrode opening **304** may have a substantially larger width in the x-direction (W_{tub_x}) and/or y-direction (W_{tub_y}) than IC component contact openings **302**. The shape and dimensions of the tub opening region **306** may be selected based on various parameters, e.g., for effective manufacturing of the MIM capacitor module **100** (e.g., effective formation of the outer electrode **102**, insulator **104**, and inner electrode **106** in the tub opening region **306**) and/or for desired performance characteristics of the resulting MIM capacitor module **100**. In one example, the tub opening region **306** may have a square or rectangular shape from the top view. In other examples, tub opening region **306** may have a circular or oval shape from the top view.

[0065] As noted above, a width of tub opening region **306** in the x-direction (W_{tub_x}), y-direction (W_{tub_y}), or both the x-direction and y-direction (W_{tub_x} and W_{tub_y}) may be substantially larger than the width $W_{contact}$ of IC component contact openings **302** in the x-direction, y-direction, or both the x-direction and y-direction. For example, in some examples, each width W_{tub_x} and W_{tub_y} of tub opening region **306** is at least twice as large as the width $W_{contact}$ of IC component contact openings **302**. In particular examples, each width W_{tub_x} and W_{tub_y} of tub opening region **306** is at least five times as large, or at least 10 times as large, as the width $W_{contact}$ of IC component contact openings **302**. In some examples, W_{tub_x} and W_{tub_y} are each in the range of 1-100 μm .

[0066] Further, tub opening region **306** may be formed with a height-to-width aspect ratio of less than or equal to 1.0 in both the x-direction and y-direction, e.g., to allow effective filling of the tub opening region **306** by conformal materials. For example, tub opening region **306** may be formed with aspect ratios H_{tub}/W_{tub_x} and H_{tub}/W_{tub_y} respectively in the range of 0.01-1.0, for example in the range of 0.1-1.0. In some examples, aspect ratios H_{tub}/W_{tub_x} and H_{tub}/W_{tub_y} are respectively less than or equal to 1.0, e.g., for effective filling of tub opening region **306** by conformal materials, e.g., tungsten or silicon nitride. For example, tub opening region **306** may be formed with aspect ratios H_{tub}/W_{tub_x} and H_{tub}/W_{tub_y} respectively in the range of 0.1-1.0, or more particularly in the range of 0.5-1.0.

[0067] The extension opening region **308** of the outer electrode opening **304** has an x-direction width W_{ext_x} and a y-direction width W_{ext_y} . The x-direction width W_{ext_x} may be in the range of 1-10 μm , and y-direction width W_{ext_y} may be in the range of 0.1-0.5 μm . In some examples, W_{ext_y} may be the same as $W_{contact}$. In other examples, W_{ext_y} may be greater than $W_{contact}$.

[0068] Next, as shown in FIG. 3C, a liner (or “glue layer”) **103**, e.g., comprising TiN with a thickness in the range of 50 Å-200 Å, is deposited over the structure and extends down into respective IC component contact openings **302** and outer electrode opening **304**, including tub opening region **306** and extension opening region **308**. A conformal metal layer **320** is deposited over the liner **103** and extends down into respective IC component contact openings **302** and outer electrode opening **304**, including tub opening region **306** and extension opening region **308**. The deposited conformal metal layer **320** (a) fills respective IC component

contact openings 302 to form respective IC component contacts 206, (b) partially fills the tub opening region 306 of the outer electrode opening 304 to form an outer electrode cup 324 in the tub opening region 306, and (c) fills the extension opening region 308 of the outer electrode opening 304 to form the outer electrode extension structure 108 (more clearly shown in FIG. 3D, discussed below) in the extension opening region 308.

[0069] The outer electrode cup 324 includes a laterally-extending outer electrode cup base 326 and a plurality of vertically-extending outer electrode sidewalls 114 extending upwardly (in the z-direction) from a lateral perimeter edge of the laterally-extending outer electrode cup base 326. The outer electrode extension structure 108 extends laterally (in the x-direction) from a vertically-extending outer electrode sidewall 114.

[0070] In some examples, the conformal metal layer 320 comprises tungsten deposited with a thickness in the range of 1000 Å-5000 Å. In other examples, the conformal metal layer 320 may comprise Co, TiN, or other conformal metal. The conformal metal layer 320 may be deposited by a conformal chemical vapor deposition (CVD) process or other suitable deposition process.

[0071] As shown in FIGS. 3D (top view) and FIG. 3E (cross-sectional side view through line 3E-3E shown in FIG. 3D), an etch process is performed to remove the laterally-extending outer electrode cup base 326 (and underlying liner 103), along with portions of the conformal metal layer 320 (and underlying liner 103) outside (i.e., above) the IC component contact openings 302 and outer electrode opening 304. In some examples, the etch process may comprise an anisotropic dry etch. The etch process may expose an upper surface 330 of the lower dielectric region 120 (e.g., STI field oxide region).

[0072] As shown in FIGS. 3D and 3E, after the etch process, the conformal metal layer 320 remaining in the tub opening region 306 defines the outer electrode 102 including a plurality of vertically-extending outer electrode sidewalls 114a-114d extending upwardly from the lower dielectric region 120 (e.g., STI field oxide region). In this example, the vertically-extending outer electrode sidewalls 114a-114d define a closed-loop perimeter in the horizontal (x-y) plane, as shown in FIG. 3D. The outer electrode extension structure 108 extends laterally (in the x-direction) from the vertically-extending outer electrode sidewall 114a.

[0073] As shown in FIG. 3F, an insulator layer 340 is deposited over the structure and extends down into an opening 342 defined by the outer electrode sidewalls 114a-114d to form insulator 104, which may be cup-shaped. The insulator 104 includes (a) the laterally-extending insulator base 118 formed on the upper surface 330 of the lower dielectric region 120 and (b) the vertically-extending insulator sidewalls 116a-116d extending upwardly from the laterally-extending insulator base 118. In this example, the insulator sidewalls 116a-116d extend upwardly from a lateral perimeter edge of the laterally-extending insulator base 118. In some examples, insulator layer 340 comprises silicon nitride (SiN) deposited with a thickness in the range of 250 Å-750 Å by a Plasma Enhanced Chemical Vapor Deposition (PECVD) process. Alternatively, insulator layer 330 may comprise Al_2O_3 , ZrO_2 , HfO_2 , ZrSiO_x , HfSiO_x , HfAlO_x , or Ta_2O_5 , or other suitable capacitor insulator material deposited using an Atomic Layer Deposition (ALD) process.

[0074] In another example, the laterally-extending insulator base 118 may be removed, while leaving the vertically-extending insulator sidewalls 116a-116d substantially intact, such that the resulting insulator 104 includes vertically-extending insulator sidewalls 116a-116d extending upwardly from dielectric region 120, without the laterally-extending insulator base 118. For example, the laterally-extending insulator base 118 may be removed by an anisotropic etch that leaves the vertically-extending insulator sidewalls 116a-116d substantially intact.

[0075] As shown in FIG. 3G, an inner electrode layer 350 is deposited over the insulator layer 340 and extends into and fills an opening 352 defined by the insulator 104, which as indicated above is cup-shaped, the inner electrode layer 350 thereby forming inner electrode 106 within opening 352. In some examples, inner electrode layer 350 may comprise Al, Ti, TiN, W, or a combination thereof, for example TiN and Al, and may be deposited by a physical vapor deposition (PVD) process.

[0076] As shown in FIG. 3H, a planarization process, e.g., chemical mechanical planarization (CMP) process, is performed to remove upper portions of the inner electrode layer 350 and insulator layer 340. The planarization process defines a planarized upper surface 356 and defines a final form of the vertically-extending IC component contacts 206, outer electrode 102, insulator 104, inner electrode 106, and outer electrode extension structure 108.

[0077] As shown in FIG. 3I, an etch stop layer 230 is deposited on the planarized upper surface 356 defined by the planarization process. In some examples, etch stop layer 230 may comprise SiN, SiC, or suitable high-k dielectric film (e.g., having a dielectric constant above 7.0), and may be deposited with a thickness in the range of 250 Å-750 Å. Etch stop layer 230 may function to terminate an edge of the electric field generated by the MIM capacitor module 100. As a result, the inclusion of the etch stop layer 230 may relieve unwanted electric field edge effects near the planarized upper surface 356 and thereby increase the breakdown voltage of the MIM capacitor module 100. In addition, the etch stop layer 230 may function as a diffusion barrier to reduce diffusion from the inner electrode 106, e.g., where the inner electrode 106 is formed from copper or other diffusion prone metal.

[0078] Next, as shown in FIG. 3J, the upper metal layer M_x , including the IC component connection element 208, inner electrode contact element 110, and outer electrode contact element 112, is formed, e.g., by a damascene process. In one example, upper metal layer M_x comprises a copper interconnect layer formed by a copper damascene process.

[0079] To form the upper metal layer M_x , dielectric layer 232 is deposited over the etch stop layer 230. In some examples, dielectric layer 232 may comprise silicon oxide, FSG (FluoroSilicate Glass), OSG (OrganoSilicate Glass), or porous OSG. Dielectric layer 232 may be patterned and etched to form (a) an IC component connection element opening 360 (e.g., trench opening) above IC component contacts 206, (b) an inner electrode contact opening 362 above the inner electrode 106, and (c) an outer electrode contact opening 364 above the outer electrode extension structure 108.

[0080] Openings 360, 362, and 364 may be formed using a plasma etch or other suitable etch, followed by a resist strip or other suitable process to remove remaining portions of

photoresist material. The depth of openings **360**, **362**, and **364** may be controlled by the etch stop layer **230**, e.g., to stop at a depth just below the etch stop layer **230** to thereby expose (a) a respective top surface area of each IC component contact **206**, (b) expose a top surface area of inner electrode **106**, and (c) a top surface area of outer electrode extension structure **108**.

[0081] Barrier layer **130** (e.g., a TaN/Ta bilayer) and a copper seed layer may be deposited over the dielectric layer **232** and extends down into the openings **360**, **362**, and **364**. A copper plating process may then be performed, which fills the openings **360**, **362**, and **364** with copper. A copper anneal may be performed, followed by a copper CMP process to remove portions of the copper above openings **360**, **362**, and **364**, thereby defining (a) the IC component connection element **208** electrically connected to the IC component contacts **206**, (b) the inner electrode contact element **110** electrically connected to the inner electrode **106**, and (c) the outer electrode contact element **112** electrically connected to the outer electrode extension structure **108**. In other examples, others metal (other than copper) suitable for damascene processing may be used to form the IC component connection element **208**, inner electrode contact element **110**, and outer electrode contact element **112**, for example, tungsten (W), cobalt (Co), or aluminum (Al).

[0082] After forming the upper metal layer M_x as discussed above, the process may continue to construct additional interconnect structures, e.g., by constructing additional metal layers separated by respective dielectric layers.

[0083] With reference to the completed MIM capacitor module **100** shown in FIG. 3J, as discussed above (e.g., with respect to FIGS. 1A-1C and FIGS. 2A-2B) the inner electrode **106** is capacitively coupled to respective vertically-extending outer electrode sidewalls **114a-114d** through respective vertically-extending insulator sidewalls **116a-116d** to effectively define four vertical-plate capacitor units, indicated generally at VPC_1 - VPC_4 , each creating a horizontally-extending electric field “E” extending in the x-direction or y-direction.

1-12. (canceled)

13. A method, comprising:

forming an outer electrode opening in a dielectric region, the outer electrode opening including a tub opening region and an extension opening region extending laterally from the tub opening region;

depositing a conformal metal layer over the dielectric region and extending down into the outer electrode opening to form (a) an outer electrode cup in the tub opening region and (b) an outer electrode extension structure in the extension opening region;

wherein the outer electrode cup includes a laterally-extending outer electrode cup base and a plurality of vertically-extending outer electrode sidewalls extending upwardly from the laterally-extending outer electrode cup base;

wherein the outer electrode extension structure extends laterally from a particular vertically extending outer electrode sidewall of the plurality of vertically-extending outer electrode sidewalls;

depositing an insulator layer forming a cup-shaped insulator in an opening defined by the plurality of vertically-extending outer electrode sidewalls, the cup-shaped insulator including a laterally-extending insulator base and a plurality of vertically-extending

insulator sidewalls extending upwardly from the laterally-extending insulator base;

depositing an inner electrode layer over the insulator layer and extending into an opening defined by the cup-shaped insulator;

performing a planarization process to remove upper portions of the insulator layer and inner electrode layer, wherein a remaining portion of the inner electrode layer defines an inner electrode; and

forming a metal layer including (a) an inner electrode contact element electrically connected to the inner electrode and (b) an outer electrode contact element electrically connected to the outer electrode extension structure.

14. The method of claim 13, comprising performing an etch process to remove the laterally-extending outer electrode cup base prior to depositing the insulator layer.

15. The method of claim 14, wherein:

forming the outer electrode opening in the dielectric region exposes a dielectric surface at a bottom of the tub opening region; and

depositing the insulator layer forming the cup-shaped insulator comprises depositing the laterally-extending insulator base on the exposed dielectric surface at the bottom of the tub opening region.

16. The method of claim 13, comprising, prior to forming the metal layer, depositing an etch stop layer on a planarized surface defined by the planarization process.

17. The method of claim 13, comprising:

forming an integrated circuit (IC) component contact opening in the dielectric region, the IC component contact opening laterally spaced apart from the outer electrode opening, the IC component contact opening exposing an underlying IC component;

wherein the deposited conformal metal layer extends down into the IC component contact opening to form a vertically-extending IC component contact; and

wherein the metal layer includes (a) the inner electrode contact element electrically connected to the inner electrode, (b) the outer electrode contact element electrically connected to the outer electrode extension structure, and (c) an IC component connection element electrically connected to the IC component contact.

18. The method of claim 17, wherein the IC component comprises a silicided polysilicon structure.

19. The method of claim 17, wherein the IC component comprises a transistor component.

20. A method, comprising:

forming an extended outer electrode structure including (a) an outer electrode including an outer electrode a plurality of outer electrode sidewalls; and (b) an outer electrode extension structure extending laterally from a respective outer electrode sidewall;

forming an insulator in an interior opening of the outer electrode defined by the plurality of outer electrode sidewalls, the insulator including a plurality of insulator sidewalls;

forming an inner electrode in an interior opening of the insulator defined by the plurality of insulator sidewalls; wherein respective insulator sidewalls are arranged between the inner electrode and respective outer electrode sidewalls; and

forming an inner electrode contact element and an outer electrode contact element, wherein the inner electrode

contact element is electrically connected to the inner electrode, and the outer electrode contact element is electrically connected to the outer electrode extension structure.

21. The method of claim **20**, wherein forming the extended outer electrode structure comprises:

forming an outer electrode cup including a laterally-extending outer electrode base and the plurality of outer electrode sidewalls extending upwardly from the outer electrode base; and

removing the outer electrode base prior to forming the insulator.

22. The method of claim **21**, comprising performing an etch process to remove the laterally-extending outer electrode base.

23. The method of claim **21**, wherein:

removing the outer electrode base exposes an underlying dielectric region; and

forming the insulator comprises depositing an insulator layer in the interior opening of the outer electrode defined by the plurality of outer electrode sidewalls, wherein the deposited insulator layer includes a laterally-extending insulator base on the exposed dielectric region and the plurality of insulator sidewalls extending upwardly from the laterally-extending insulator base.

24. The method of claim **20**, wherein forming the extended outer electrode structure comprises:

forming an outer electrode opening in a dielectric region, the outer electrode opening including a tub opening region and an extension opening region extending laterally from the tub opening region; and

depositing a conformal metal layer over the dielectric region and extending down into the outer electrode opening to form (a) an outer electrode cup structure in the tub opening region and (b) the outer electrode extension structure in the extension opening region.

25. The method of claim **20**, wherein:

forming the insulator comprises depositing an insulator layer extending into the interior opening of the outer electrode to form a cup-shaped insulator; and

forming the inner electrode comprises depositing an inner electrode layer over the insulator layer and extending into an opening defined by the cup-shaped insulator.

26. The method of claim **25**, comprising performing a planarization process to remove upper portions of the insulator layer and inner electrode layer, wherein a remaining portion of the inner electrode layer defines an inner electrode.

27. The method of claim **20**, wherein forming the inner electrode contact element and the outer electrode contact element comprises forming a metal layer extending over the forming an extended outer electrode structure, the metal layer including the inner electrode contact element and the outer electrode contact element.

28. The method of claim **20**, comprising forming a vertically-extending integrated circuit (IC) component con-

tact concurrently with the extended outer electrode structure in a dielectric region, the vertically-extending IC being laterally spaced apart from the extended outer electrode structure in the dielectric region.

29. The method of claim **28**, comprising forming a metal layer extending over the forming an extended outer electrode structure, the metal layer including (a) the inner electrode contact element, (b) the outer electrode contact element, and (c) an IC component connection element electrically connected to the IC component contact.

30. A method, comprising:

forming an outer electrode opening in a dielectric region, the outer electrode opening including a tub opening region and an extension opening region extending laterally from the tub opening region;

depositing a conformal metal layer over the dielectric region and extending down into the outer electrode opening to form (a) an outer electrode cup in the tub opening region and (b) an outer electrode extension structure in the extension opening region;

wherein the outer electrode cup includes a laterally-extending outer electrode cup base and a plurality of vertically-extending outer electrode sidewalls extending upwardly from the laterally-extending outer electrode cup base;

wherein the outer electrode extension structure extends laterally from a particular vertically extending outer electrode sidewall of the plurality of vertically-extending outer electrode sidewalls;

at least partially removing the laterally-extending outer electrode cup base to expose an underlying surface;

depositing an insulator layer forming a cup-shaped insulator in an opening defined by the plurality of vertically-extending outer electrode sidewalls, the cup-shaped insulator including a laterally-extending insulator base formed on the exposed underlying surface and a plurality of vertically-extending insulator sidewalls extending upwardly from the laterally-extending insulator base; and

depositing an inner electrode layer over the insulator layer and extending into an opening defined by the cup-shaped insulator.

31. The method of claim **30**, wherein the exposed underlying surface comprises a dielectric surface, wherein the laterally-extending insulator base is formed on the exposed dielectric surface.

32. The method of claim **30**, comprising:

forming an integrated circuit (IC) component contact opening in the dielectric region;

wherein the deposited conformal metal layer extends down into the IC component contact opening to form a vertically-extending IC component contact laterally spaced apart from the outer electrode cup

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